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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**
Norio KIMURA et al. : Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS
AND SUBSTRATE POLISHING METHOD

ELECTION OF INVENTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of January 8, 2004, applicants in the above-referenced application hereby elect the invention Group II corresponding to claims 16-37.

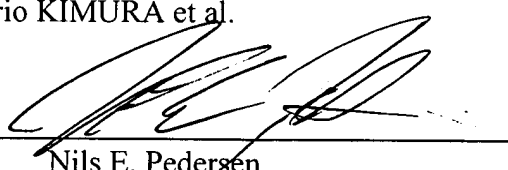
An early and favorable action on their merits is requested.

Respectfully submitted,

Norio KIMURA et al.

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

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